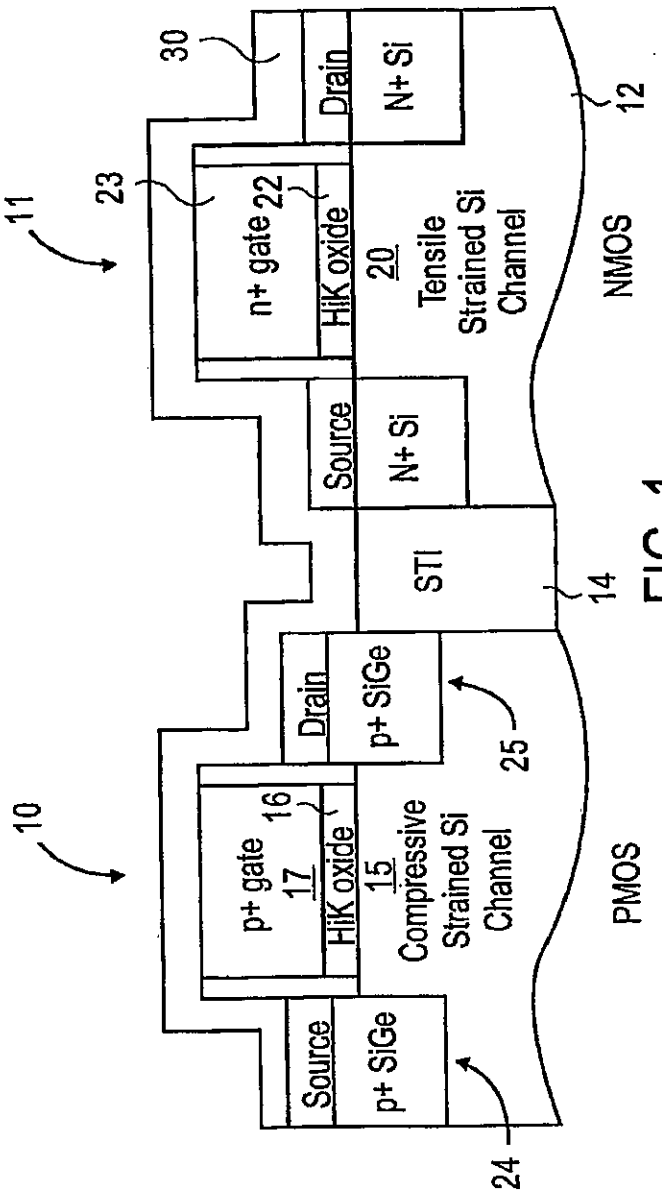


FIG. 1
(PRIOR ART)

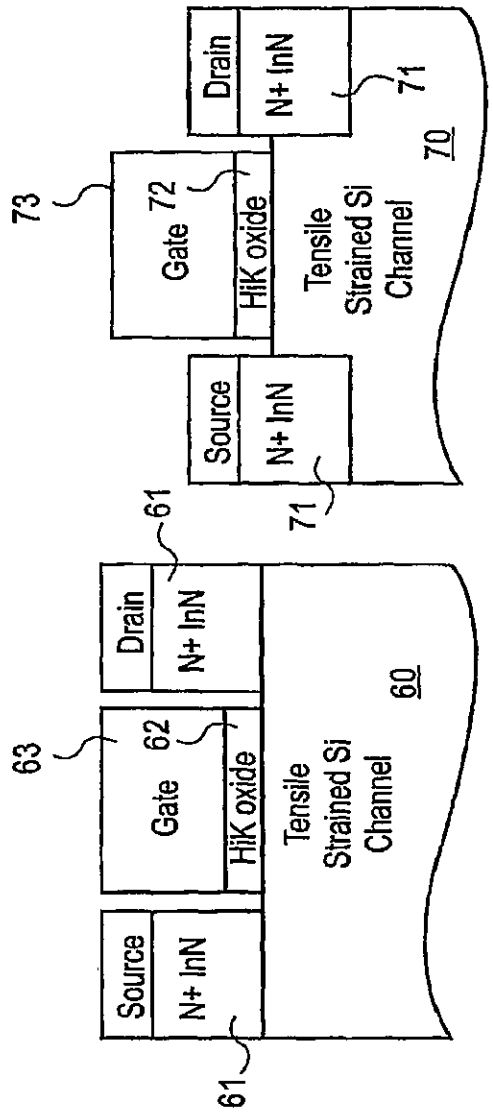


FIG. 2

FIG. 3

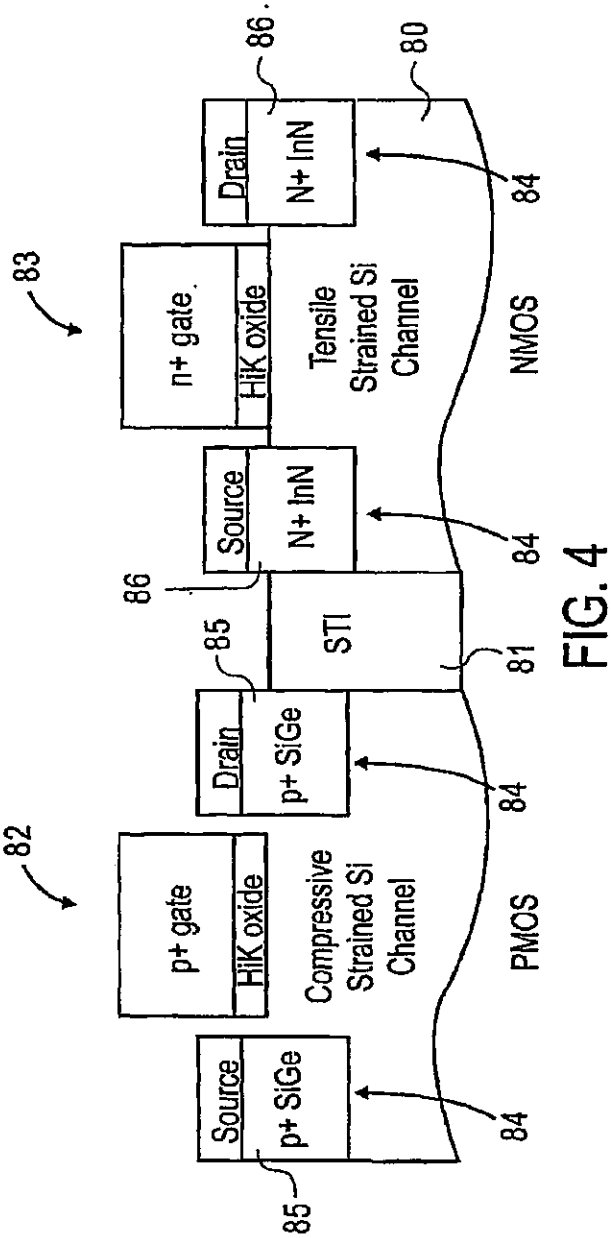


FIG. 4

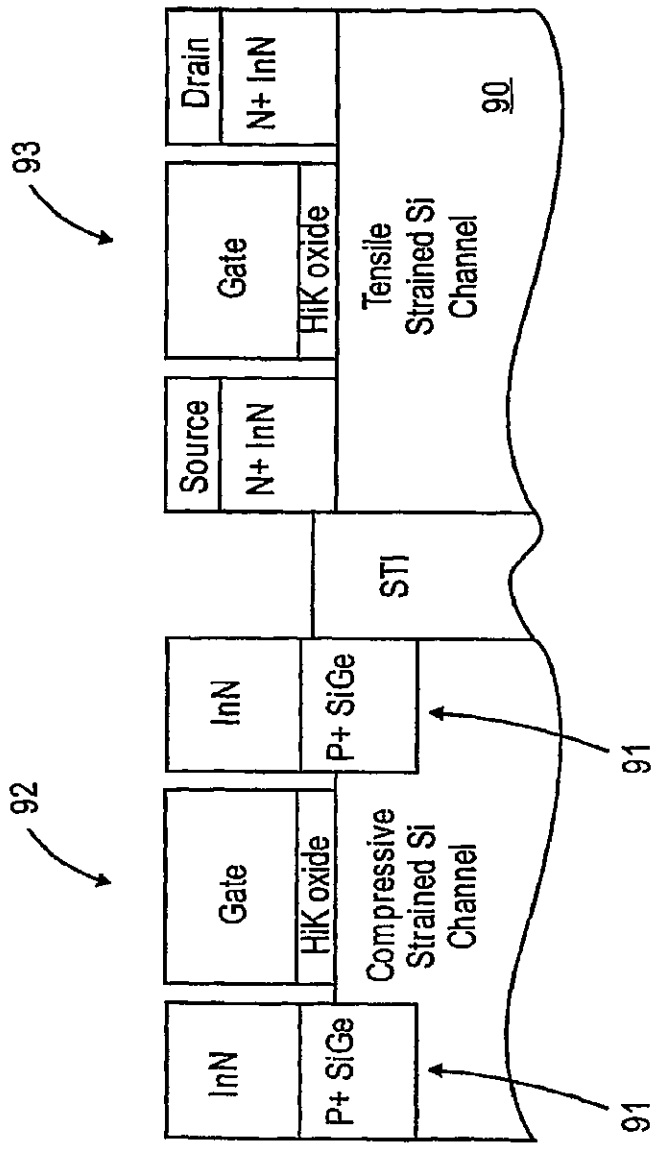

93
92
Drain
N+ InN
Gate
HiK oxide
Source
N+ InN
Tensile
Strained Si
Channel
90
STI
InN
P+ SiGe
Gate
HiK oxide
Compressive
Strained Si
Channel
InN
P+ SiGe
91
91

FIG. 5